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the following are the papers presented/accepted for publication from this work :

- 1) Comparison of refractive index and adhesion of porous Al_2O_3 thin films obtained from oxidation of aluminium films in steam and in hot water .
D. M. Bendale, P. V. Patil, R. K. Puri, Vijaya Puri.
'Communication in Instrumentation', In Press.
- 2) Refractive index and adhesion of Al_2O_3 thin films obtained from different processes --a comparative study.
P. V. Patil, D. M. Bendale, R. K. Puri, Vijaya Puri.
'Thin solid films' (Accepted for publication), 1995.
- 3) Ambient aging effects in Al_2O_3 thin films deposited by electron beam evaporation and steam oxidised aluminium films : a comparative study.
P. V. Patil, D. M. Bendale, R. K. Puri, Vijaya Puri.
'National Conference on Development in Electronic Materials and their Application', (March 95) Kolhapur.
- 4) Refractive index changes of steam oxidised and hot water oxidised porous Al_2O_3 thin films due to heat and moisture cycling.
D. M. Bendale, R. K. Puri, Vijaya Puri.
'Material Research Society of India', (Feb. 96) Bangalore.

5) Electrical behaviour of steam oxidised and hot water oxidised porous Al_2O_3 thin films under humidity ambient.

D. M. Bendale, R. K. Puri, Vijaya Puri.

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